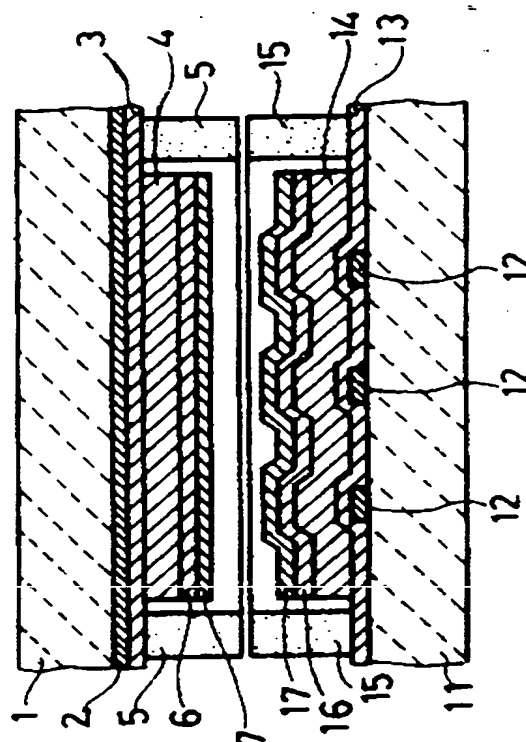


## Patent Abstracts of Japan

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 INVENTOR : OTSUKA AKIRA;  
  
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 PANEL



**ABSTRACT :** **PURPOSE:** To obtain stable performance characteristics of a panel and promote an extension of its life, by forming surface layers made of MgO on dielectric layers in a vapor deposition device where oxygen gas is introduced.

**CONSTITUTION:** Fully on surfaces of glass base boards 1, 11 on which an X-electrode 2 and Y-electrode 12 are formed, thin dielectric layers 3 and 13 are formed, and further on their top surfaces the second dielectric layers 4 and 14 are formed. Then seal material layers 5 and 15 are formed, and evaporated films (topmost dielectric layers) 6 and 16 are deposited. Successively on their clean top surfaces, surface layers 7 and 17 made of MgO are formed. A forming work of the surface layers 7 and 17 is performed by evaporating the MgO in a vapor-deposition device where oxygen gas is introduced.

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